



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE 2 202

TC 2800 HAIL ROOM

Application of

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2/28/02

Takashi NIWA et al.

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Serial No. 09/740,664

Filed: December 19, 2000

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For: NEAR-FIELD OPTICAL PROBE

AND MANUFACTURING METHOD FOR SAME, AND NEAR-FIELD

OPTICAL APPARATUS USING

THE NEAR-FIELD PROBE

Docket No. S004-4168

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COMMISSIONER OF PATENTS AND TRADEMARKS Washington, DC 20231

PRELIMINARY AMENDMENT

S I R:

In order to place this application in better condition for a complete examination on the merits, applicants preliminarily amend their application as follows:

IN THE SPECIFICATION:

Please replace the paragraph beginning at page 1, line 19, with the following rewritten paragraph:

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A scanning-type near-field atomic microscope has also been proposed which uses an optical fiber probe formed in a hook form as a cantilever for an atomic force microscope

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